RΘ-A300-HW: Motorized stage for fast mapping of coatings on Heavy Substrates

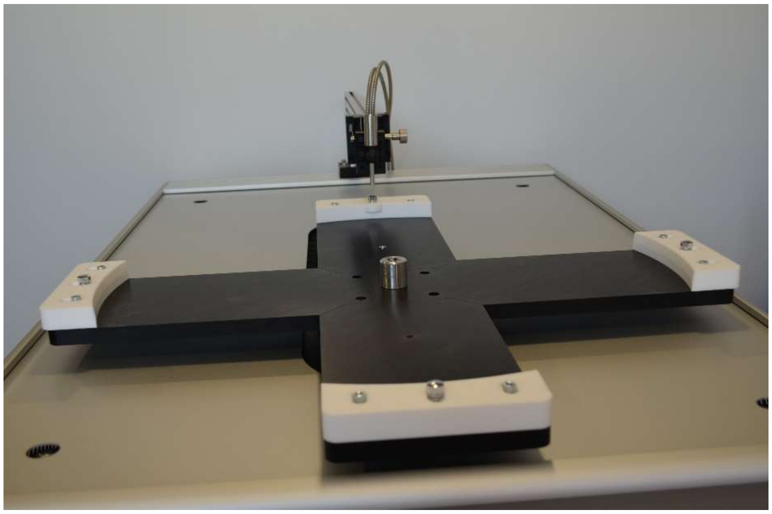
ARΘ-A300 HW is a powerful motorized stage operating in Polar coordinates. It can accommodate any standard wafer up to 300mm in diameter. It is operated through any FR-pRo unit and it comes along with one vacuum chuck.

Applications

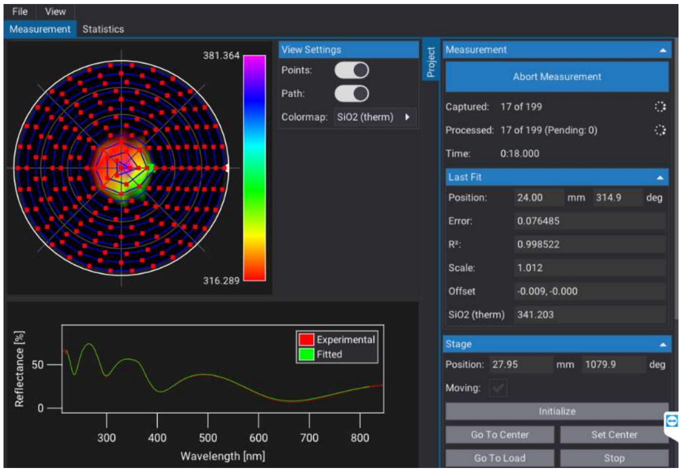
- Mapping of thickness, refractive index, colour etc of any standard wafer up to 300mm in diameter.
- Characterization of areas with small size or patterned areas
- Rough coatings
- Uneven samples
- Scattering samples

Features

- 300measurements /min on 8inch wafer
- Accuracy: 5μm / 0.1°
- User Friendly software for fast routine operation.
- FR-Mic module can be further attached for ultra-small spot size



The **RΘ-150 stage** is a stable-top unit for the automatic characterization of coatings on wafers. It is operated through any FR-pRo unit and operates either under FR-Monitor or via the independent software that has been especially developed for daily routine use. The maximum scanning speed on 8inch wafers is 300points/min and 625measurements/90sec.



Points: ●
Path: ●
Colormap: SiO2 (therm)

Captured: 17 of 199
Processed: 17 of 199 (Pending: 0)
Time: 0:18.000

Position: 24.00 mm 314.9 deg
Error: 0.076485
R²: 0.998522
Scale: 1.012
Offset -0.009, -0.000
SiO2 (therm) 341.203

Position: 27.95 mm 1079.9 deg
Moving: ☐

*Available in RΘ-200 configuration also